

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Beaman et al.

Application No.: 10/733,523

Confirmation No.: 9060

Filed: December 10, 2003

Art Unit: 1762

For: METHODS AND SYSTEMS FOR
CONTROLLING TEMPERATURE DURING
MICROFEATURE WORKPIECE
PROCESSING, E.G., CVD DEPOSITION

Examiner: D. P. Turocy

INFORMATION DISCLOSURE STATEMENT (IDS)

MS RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO/SB/08. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement, pursuant to 37 CFR 1.114(c), accompanies the Request for Continued Examination (37 CFR 1.114) submitted herewith.

In accordance with 37 CFR 1.98(a)(2)(ii), Applicants have not submitted copies of U.S. patents and U.S. patent applications. Applicants submit herewith copies of foreign patents and non-patent literature in accordance with 37 CFR 1.98(a)(2).

In accordance with 37 CFR 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 CFR 1.56(a) exists. In accordance with 37 CFR 1.97(h), the filing of this Information Disclosure Statement shall not be construed to be an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

It is submitted that the Information Disclosure Statement is in compliance with 37 CFR 1.98 and the Examiner is respectfully requested to consider the listed references.

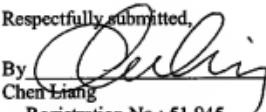
The Director is hereby authorized to charge any deficiency in the fees filed, asserted to be filed or which should have been filed herewith (or with any paper hereafter filed in this application by this firm) to our Deposit Account No. 50-0665, under Order No. 108298718US.

Dated: 3/9/07

Respectfully submitted,

By

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Sheet 1 of 4 Attorney Docket Number 108298718US

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Examiner Initials*	Case No.†	Foreign Patent Document		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Column, Lines, Where Relevant Passages or Relevant Figures Appear	TP
		Country Code* Number* Kind Code* (If Known)	MM-DD-YYYY				
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Complete if Known

Application Number	10/733,523-Conf. #9060
Filing Date	December 10, 2003
First Named Inventor	Kevin L. Beaman
Art Unit	1762
Examiner Name	D. P. Turocy

Attorney Docket Number 108298718US

NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
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